

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Takenori HIROSE, et al.

Application No.: 10/081,385

Filed: February 20, 2002

For: FILM THICKNESS MEASURING  
METHOD AND APPARATUS, AND THIN  
FILM DEVICE MANUFACTURING  
METHOD AND MANUFACTURING  
APPARATUS USING SAME

Customer No.: 20350

Confirmation No. 9702

Examiner: Hwa S. Lee

Technology Center/Art Unit: 2877

AMENDMENT

Mail Stop **Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

April 9, 2007

Sir:

In response to the Office Action mailed November 9, 2006, please enter the following amendments and remarks:

**Amendments to the Claims** are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks/Arguments** begin on page 4 of this paper.